

FAST - (Untitled1-1)

File View Edit Tools Window Help

☐ L5: (75326) 4 and (substrate.clm.▲  
☐ L6: (5080) 5 and (lift\$4 with (sv  
☐ L7: (5080) 6 and (electronic or c  
☐ L8: (2251) 7 and (lift\$4.clm. or  
☐ L9: (830) 8 and (electronic\$1.clm  
☐ L10: (169) 9 and (gravit\$4 or vib  
☐ L11: (22) 10 and (vibration\$2 and  
☐ Failed  
☐ (O) 5 and (electronic\$1.clm. or c

Search      
 DB: USPAT:USPGPUB ☒ Purals  
 Default operator: OR ☒ Highlight all hit terms initially  
 10 and (vibration\$2 and gravit\$4)

	U	D	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	
6	<input type="checkbox"/>	<input type="checkbox"/>	US 6387184 B1	20020514	22	System and method for interchangeably interfacing wet	118/323	118/301; 118/302;	
7	<input type="checkbox"/>	<input type="checkbox"/>	US 6331885 B1	20011218	88	Stage apparatus, scanning type exposure apparatus, and device	355/53	356/399; 356/400;	
8	<input type="checkbox"/>	<input type="checkbox"/>	US 6261433 B1	20010717	23	Electro-chemical deposition system and method of electroplating on	205/96	204/230.2; 204/230.7;	
9	<input type="checkbox"/>	<input type="checkbox"/>	US 5651176 A	19970729	13	Vibratory feeder trays and synchronous mass production	29/740	198/763; 29/759;	
10	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5546375 A	19960813	30	Method of manufacturing a tip for scanning tunneling microscope using	369/126	216/11; 250/306;	
11	<input type="checkbox"/>	<input type="checkbox"/>	US 5099820 A	19920331	13	Abrasion-type splitting unit	125/16.01	125/16.02; 125/23.01;	
12	<input type="checkbox"/>	<input type="checkbox"/>	US 5044871 A	19910903	20	Integrated circuit processing system	414/805	118/500; 118/719;	
13	<input type="checkbox"/>	<input type="checkbox"/>	US 4966519 A	19901030	21	Integrated circuit processing system	414/805	118/500; 118/719;	
14	<input type="checkbox"/>	<input type="checkbox"/>	US 4875989 A	19891024	82	Wafer processing apparatus	204/298.33	156/345.33; 156/345.37;	
15	<input type="checkbox"/>	<input type="checkbox"/>	US 4842686 A	19890627	85	Wafer processing apparatus and method	438/709	156/345.37; 156/345.38;	
16	<input type="checkbox"/>	<input type="checkbox"/>	US 4842680 A	19890627	20	Advanced vacuum processor	216/58	156/345.29; 156/345.31;	

Office                      Microsoft

Start      FAST ... 3:00 PM